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BIB DATA SHEET

CONFIRMATION NO. 8488

10/537,133 06/02/2005 RULE APPLICANTS Toshirou Kisakibaru, Tokyo, JAPAN; Shigeru Kouchiyama, Tokyo, JAPAN; Makoto Okada, Tokyo, JAPAN; Kouta Ueno, Tokyo, JAPAN; *** CONTINUING DATA **********************************	SERIAL NUM	MBER FILING O				GROUP ART UNIT			ATTORNEY DOCKET		
APPLICANTS Toshirou Kisakibaru, Tokyo, JAPAN; Shigeru Kouchiyama, Tokyo, JAPAN; Makoto Okada, Tokyo, JAPAN; Kouta Ueno, Tokyo, JAPAN; Kouta Ueno, Tokyo, JAPAN; ***CONTINUING DATA **********************************	10/537,13			_		438		2823			
Toshirou Kisakibaru, Tokyo, JAPAN; Shigeru Kouchiyama, Tokyo, JAPAN; Makoto Okada, Tokyo, JAPAN; Kouta Ueno, Tokyo, JAPAN; This application is a 371 of PCT/JP03/02218 02/27/2003 ***FOREIGN APPLICATIONS **** JAPAN 2002-351024 12/03/2002 ***IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** Foreign Priority claimed		RUL		E							
This application is a 371 of PCT/JP03/02218 02/27/2003 *** FOREIGN APPLICATIONS ************************************	Toshirou Shigeru K Makoto O Kouta Ue	Kisakib (ouchiya kada, 7 no, Tok	ama, Tokyo, Tokyo, JAPAN Iyo, JAPAN;	JAPAN; N;							
JAPAN 2002-351024 12/03/2002 *** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** Foreign Priority claimed						2/27/2003					
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35 USC 119(a-d) conditions met 2 Yes \ No Verified and VillLIAM D COLEMANV Examiner's Signature MILLIAM D COLEMANV Examiner's Signature Initials JAPAN 34 3 3 3	** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **										
Acknowledged	35 USC 119(a-d) conditions met Yes No Verified and /WILLIAM D COLEMAN/						_				INDEPENDENT CLAIMS
BROMBERG & SUNSTEIN LLP 125 SUMMER STREET BOSTON, MA 02110-1618 UNITED STATES TITLE Air-curtain forming apparatus for wafer hermetic container in semiconductor producing device using mini-environment system FILING FEE RECEIVED 900 FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT No for following: All Fees 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) Other						JAPAN		34 3			3
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